

Message Text

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PAGE 01 STATE 119746
ORIGIN COME-00

INFO OCT-01 CIAE-00 DODE-00 EB-07 NSAE-00 USIA-06
TRSE-00 EUR-12 ERDA-05 ISO-00 SSO-00 /031 R

DRAFTED BY COMMERCE/OEA - RGAREL:JS
APPROVED BY EB/ITP/EWT - RPRACHT
RPE

-----242225Z 028968 /12
O 242128Z NAY 77
FM SECSTATE WASHDC
TO USMISSION OECD PARIS IMMEDIATE

C O N F I D E N T I A L STATE 119746

EXCON

E.O. 11652: XGDS-1

TAGS: ESTC, COCOM, PL, US

SUBJECT: US POWER SEMICONDUCTOR MANUFACTURING FACILITY TO
POLAND--IL 1355

REF: A) GAREL-TOWNSEND TELECON MAY 24
B) COCOM DOC (77) 309

FOLLOWING ARE ANSWERS TO QUESTIONS POSED BY UK:

1. PRODUCTION CAPACITY SPECIFIED IN PARA 3 OF REFDOC REPRESENTS MAXIMUM OUTPUT WHICH CAN BE ACHIEVED IN A TWO-SHIFT DAY WITH SUBJECT EQUIPMENT.
2. NO STANDBY EQUIPMENT WILL BE PROVIDED. SPARES FOR MAINTENANCE OF EQUIPMENT WILL BE LIMITED TO NORMAL QUANTITIES REQUIRED FOR A TWO-YEAR PERIOD.

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3. US APPLICANT'S INSPECTION PERSONNEL WILL BE AVAILABLE FOR PLANT INSPECTION DURING A FIVE-YEAR PERIOD, I.E., INSPECTIONS CAN BE MAINTAINED FOR A PERIOD OF THREE YEARS SUBSEQUENT TO EXPIRATION OF THE STIPULATED TWO-YEAR REQUIREMENT. THE DESCRIBED EQUIPMENT IS DESIGNED TO HANDLE POWER DEVICE GEOMETRIES AND LACKS CONTROL ACCURACIES

WHICH ARE REQUIRED FOR MICROWAVE, ELECTRO-OPTIC AND TTL/ECL
LARGE-SCALE IC DEVICE FABRICATION. VANCE

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NNN

*** Current Handling Restrictions *** n/a

*** Current Classification *** CONFIDENTIAL

Message Attributes

Automatic Decaptioning: X
Capture Date: 01-Jan-1994 12:00:00 am
Channel Indicators: n/a
Current Classification: UNCLASSIFIED
Concepts: DEVELOPMENT PROGRAMS, ENERGY, INDUSTRIAL PLANTS, PROGRESS REPORTS
Control Number: n/a
Copy: SINGLE
Sent Date: 24-May-1977 12:00:00 am
Decaption Date: 01-Jan-1960 12:00:00 am
Decaption Note:
Disposition Action: RELEASED
Disposition Approved on Date:
Disposition Case Number: n/a
Disposition Comment: 25 YEAR REVIEW
Disposition Date: 22 May 2009
Disposition Event:
Disposition History: n/a
Disposition Reason:
Disposition Remarks:
Document Number: 1977STATE119746
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Expiration:
Film Number: D770185-0625
Format: TEL
From: STATE
Handling Restrictions: n/a
Image Path:
ISecure: 1
Legacy Key: link1977/newtext/t197705107/aaaftzr.tel
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Litigation Code IDs:
Litigation Codes:
Litigation History:
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Message ID: 288f6088-c288-dd11-92da-001cc4696bcc
Office: ORIGIN COM
Original Classification: CONFIDENTIAL
Original Handling Restrictions: n/a
Original Previous Classification: n/a
Original Previous Handling Restrictions: n/a
Page Count: 2
Previous Channel Indicators: n/a
Previous Classification: CONFIDENTIAL
Previous Handling Restrictions: n/a
Reference: n/a
Retention: 0
Review Action: RELEASED, APPROVED
Review Content Flags:
Review Date: 01-Mar-2005 12:00:00 am
Review Event:
Review Exemptions: n/a
Review Media Identifier:
Review Release Date: n/a
Review Release Event: n/a
Review Transfer Date:
Review Withdrawn Fields: n/a
SAS ID: 2338749
Secure: OPEN
Status: <DBA CORRECTED> srp 970903
Subject: US POWER SEMICONDUCTOR MANUFACTURING FACILITY TO POLAND-- IL 1355
TAGS: ENRG, ESTC, PL, US, COCOM
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Type: TE
vdkgvwkey: odb://SAS/SAS.dbo.SAS_Docs/288f6088-c288-dd11-92da-001cc4696bcc
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